

## **REMARKS**

The Office Action dated September 15, 2010, has been received and carefully noted. The above amendments and the following remarks are being submitted as a full and complete response thereto.

Claims 1-12 and 14 are rejected, and Claims 13, 15, and 16 are objected to. Claim 1 is amended. Claims 1-16 are pending in this application. Support for the amendment may be found in the original specification as filed, for example at pages 20 to 23 and Figure 1. Thus, Applicants submit that no new matter is added. Applicants respectfully request reconsideration and withdrawal of the rejections.

### **Claim Rejections – 35 U.S.C. §102/§103**

Claims 1, 5-7, 9, and 14 are rejected under 35 U.S.C. §102(b) as being anticipated by Maydan (U.S. Patent No. 5,224,809, hereinafter "Maydan"); Claims 2-4 and 10 are rejected under 35 U.S.C. §103(a) as being unpatentable over Maydan; Claim 8 is rejected under 35 U.S.C. §103(a) as being unpatentable over Maydan in further view of Yoshioka (U.S. Patent Publication No. 2002/0079057, hereinafter "Yoshioka"); Claim 11 is rejected under 35 U.S.C. §103(a) as being unpatentable over Maydan in further view of Stevenson (U.S. Patent No. 5,421,979, hereinafter "Stevenson"); Claim 12 is rejected under 35 U.S.C. §103(a) as being unpatentable over Maydan and in further view of Tezuka (U.S. Patent No. 4,771,730, hereinafter "Tezuka"). Applicants note that Claim 1 has been amended. To the extent that the outstanding rejections are applicable to the amended claims, Applicants respectfully traverse the rejection.

Claim 1, as amended, recites a thin film forming apparatus comprising, among other features, a transferring device that transfers one of a substrate itself or a substrate fixing jig, and means for releasably securing the substrate itself or the substrate fixing jig, wherein the cylindrical substrate holder is rotatable around the rotating shaft which is provided in a horizontal direction; wherein the transferring device is provided outside the evacuable chamber and includes an arm insertable **into a gap between the substrate holder and the substrate fixing jig or the substrate itself**, wherein the arm, when holding the substrate fixing jig or the substrate itself, is transferred along the outer circumferential surface of the cylindrical substrate holder in a direction **parallel with the rotating shaft**; and wherein an end of one of the substrate fixing jig or the substrate itself, which is transferable by the transferring device, is fixable to the cylindrical substrate holder by the means for releasably securing. Applicants respectfully submit that Maydan, Yoshioka, Stevenson, and Tezuka, alone or in combination, do not teach or suggest all of the features recited by amended Claim 1.

The Office Action cites Maydan for teaching a robot 60 and robot actuator arm 64, which the Office Action characterizes as the transferring device recited by claim 1. Applicants respectfully submit, however, that Maydan does not teach or suggest that the robot 60 and robot actuator arm 64 is provided outside the evacuable chamber and includes an arm insertable into a gap between the substrate holder and the substrate fixing jig or the substrate itself, wherein the arm, holding the substrate fixing jig or the substrate itself, is transferrable along the outer circumferential surface of the cylindrical substrate holder in a direction in parallel with the rotating shaft; and wherein an end of

one of the substrate fixing jig or the substrate itself, which is transferable by the transferring device, is fixable to the cylindrical substrate holder by the means for releasably securing, as recited by Claim 1. Rather, as shown in Figure 5 of Maydan, the transferring device places the substrate directly onto the surface of the substrate holder and is not inserted into a gap between the substrate holder and the substrate. See also column 9, lines 62 to 65. Furthermore, the arm of the transferring device travels perpendicularly with respect to the rotating shaft of the substrate holder. See Figure 5. Therefore, Maydan does not teach or suggest all of the features recited by amended Claim 1.

Yoshioka is cited merely for teaching an apparatus in which a work piece is held and transferred in a vacuum using a magnetic force and using an evacuable transferring chamber to move a substrate from an evacuable load/lock chamber to an evacuable processing chamber. Stevenson is cited merely for teaching a sputtering process. Tezuka is cited merely for teaching sputtering, ion etching, and plasma CVD techniques for processing a substrate in a vacuum chamber. Thus, Applicants respectfully submit that Yoshioka, Stevenson, and Tezuka do not cure the above-described deficiencies of Maydan.

Claims 2-16 depend directly or indirectly from Claim 1. Applicants respectfully submit that Claims 2-16 are allowable at least for the same reasons Claim 1 is allowable, as well as for the additional subject matter recited therein. Recommended

In view of the above Applicants request withdrawal of the rejection of Claims 1, 5-7, 9, and 14 under 35 U.S.C. §102(b) over Maydan and the rejection of Claims 2-4, 8, and 10-12 under 35 U.S.C. §103(a) over Maydan, Yoshioka, Stevenson, and Tezuka.

**Allowable Subject Matter**


Applicants appreciate the Examiner's indication that Claims 13, 15, and 16 would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims.

## Conclusion

Applicants respectfully submit that this application is in condition for allowance and such action is earnestly solicited. If the Examiner believes that anything further is desirable in order to place this application in even better condition for allowance, the Examiner is invited to contact Applicants' undersigned representative at the telephone number listed below to schedule a personal or telephone interview to discuss any remaining issues.

In the event that this paper is not being timely filed, the Applicants respectfully petition for an appropriate extension of time. Any fees for such an extension, together with any additional fees that may be due with respect to this paper, may be charged to Counsel's Deposit Account Number 01-2300, referencing Docket Number 029567-00009.

Respectfully submitted,



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